

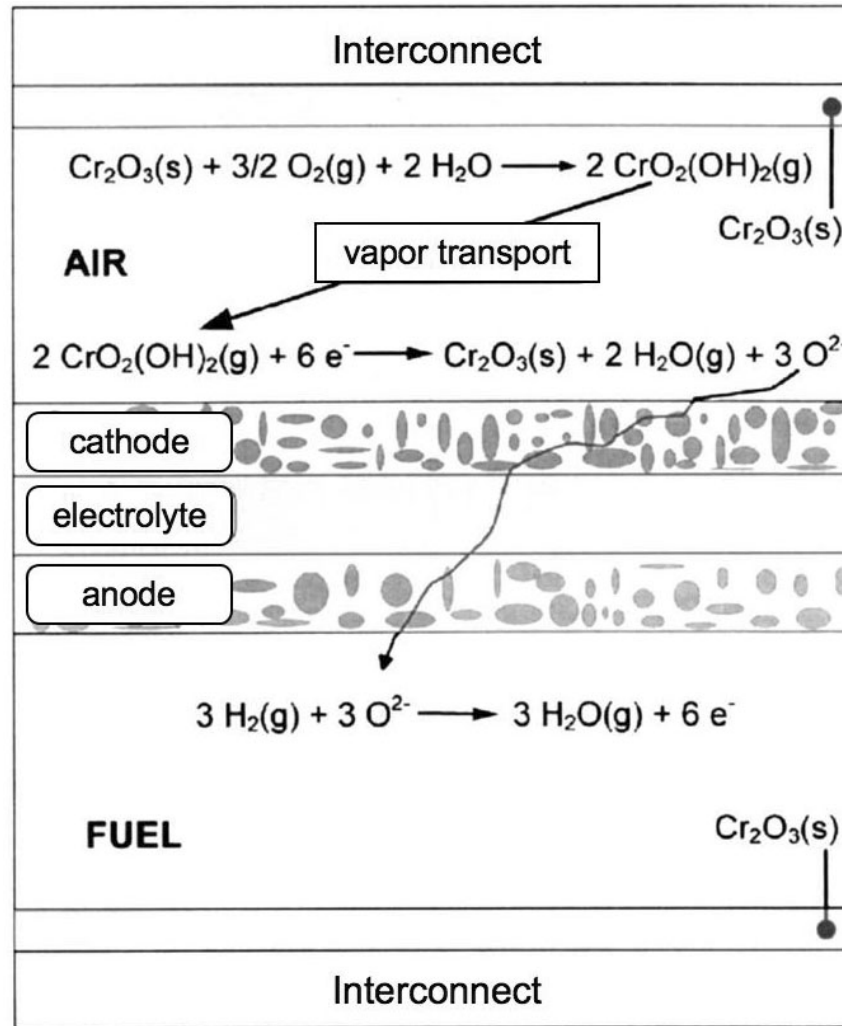
# Cathode-Interconnect Interfacial Properties

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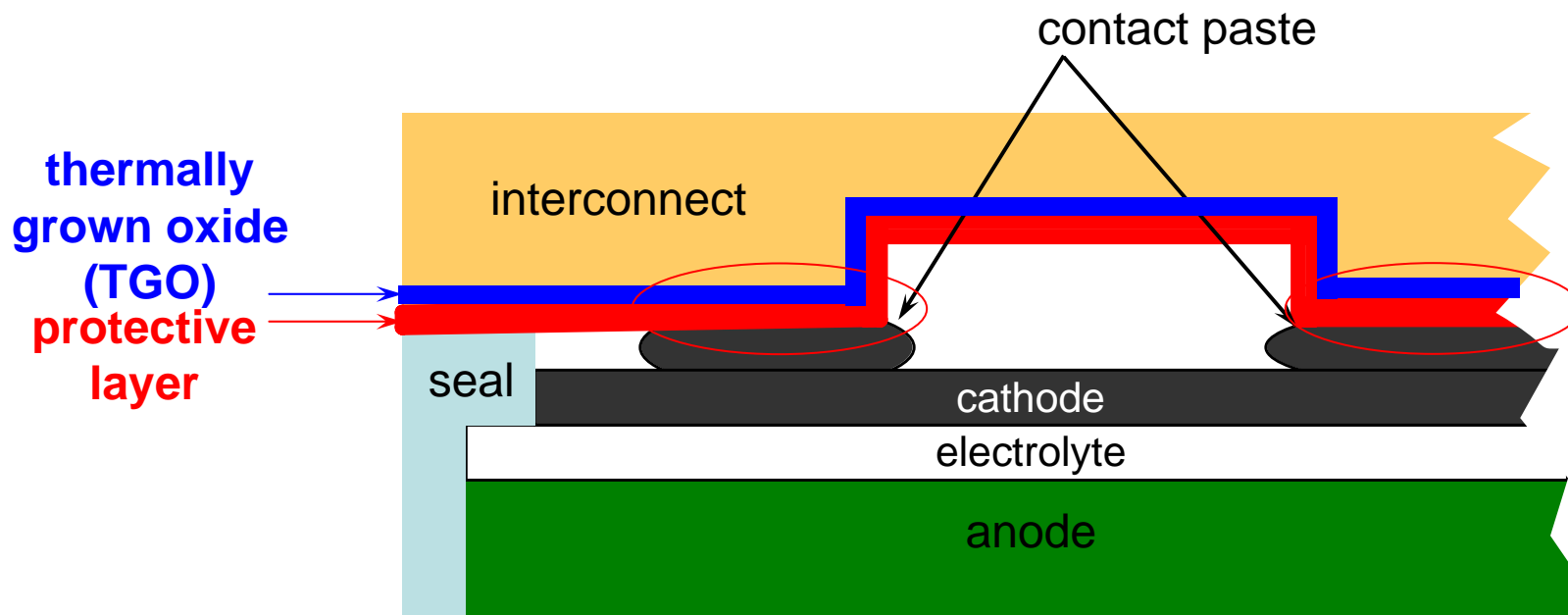
9<sup>th</sup> Annual SECA Workshop  
Pittsburgh, PA  
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# Background – Chromium poisoning



K. Hilpert, D. Das, M. Miller, D. H. Peck and R. Weiss, *J. Electrochem. Soc.*, **Vol. 143**, No. 11 (1996) pp. 3642-3647

# Background - Cathode side interfaces



- Protective layer has several requirements\*
  - diffusion barrier, thermomechanical/chemical stability etc
- Complex system with several interfaces
- Degradation may be related to debonding due to thermal cycling

\* Wang et al., *Surface and Coating Technology*, 2006

# Approach

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- Phase ID and phase evolution in protective layer during processing\*
  - Processing includes reduction and re-oxidation (specimen preparation - PNNL)
  - Phase transitions effect the stress development in layers
  - Phases in thermally grown oxide (TGO) identified
- Fracture Characterization of the interconnect-cathode interfaces as a function of processing conditions
  - Processing includes reduction, re-oxidation and  $pO_2$  cycling\*\*
  - Effect of sintering temperature, volume fraction of pore former and geometric parameters
  - Energy release rate as a function of processing conditions

\* Wang et al., *J Electrochemical Society*, 2005.

\*\* McCarthy et al., *J Power Sources*, 2008.

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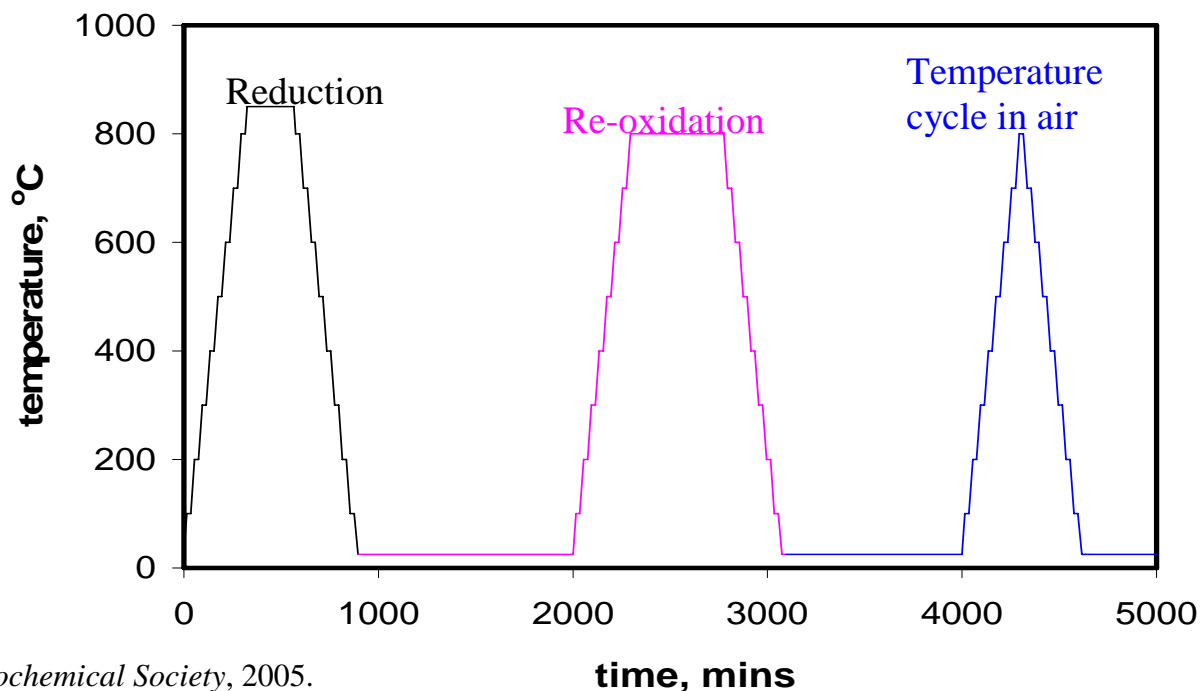
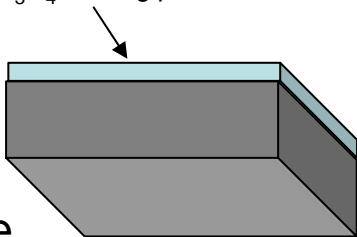
# Phase Evolution Study

# *In-situ* XRD on protective layer

## 15 $\mu\text{m}$ screen printed **(Co,Mn) oxide spinel layer**

glycine nitrate combustion synthesis using  
 $\text{MnCO}_3$  and  $\text{Co}_3\text{O}_4$  starting powders.

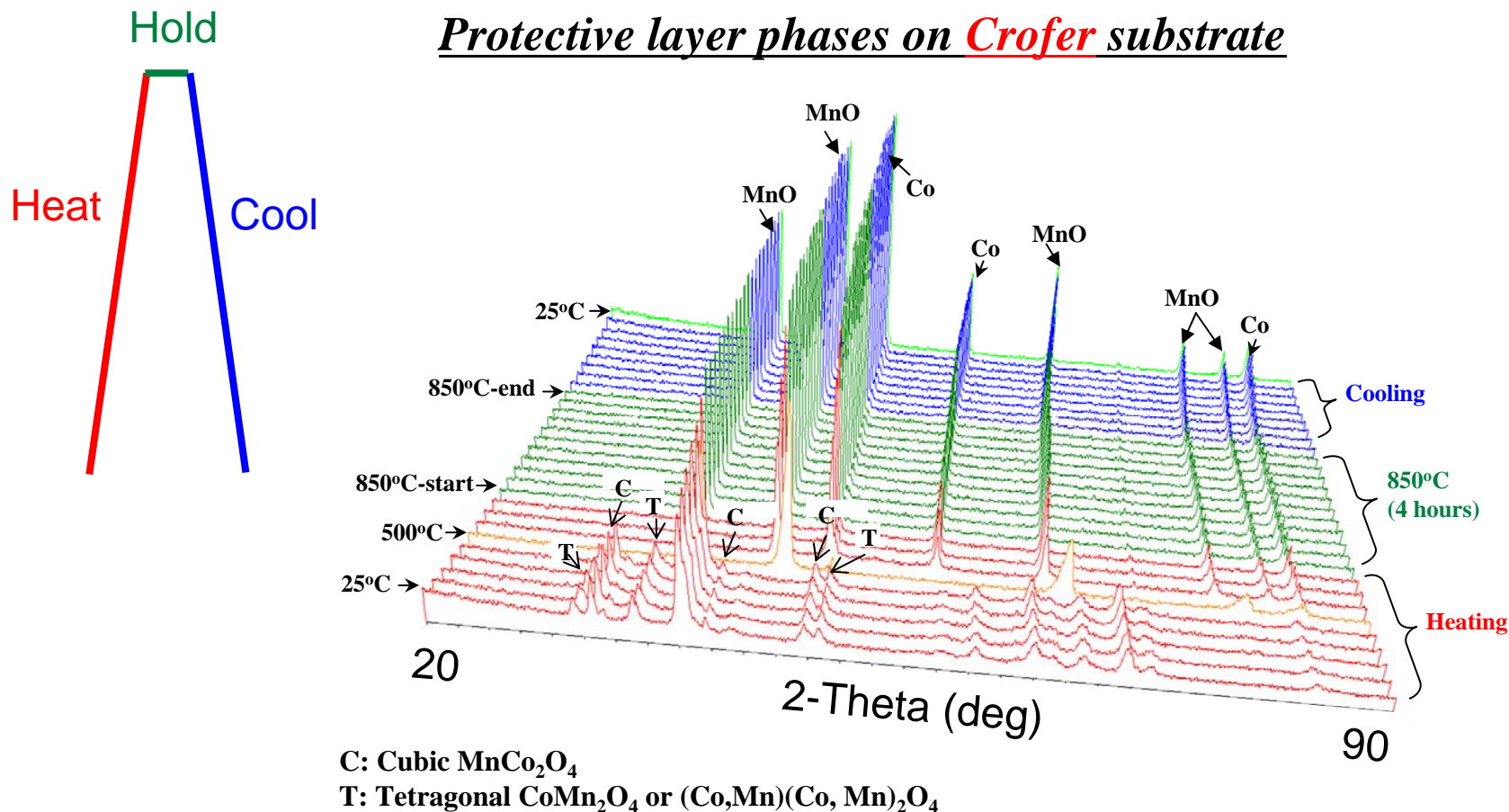
0.3 mm  
Metal  
Substrate  
(Crofer or AL441  
With Roughness,  $R_a \sim 0.3 \mu\text{m}$ )



Processing conditions from Wang et al., *J Electrochemical Society*, 2005.

	Reduction	Oxidation
Heating/Cooling Rate	5 °C/min	5 °C/min
Measurements during heating/cooling	Every 100 °C (20mins scan)	Every 100 °C (20mins scan)
Holding temperature/time	850 °C (4 hours)	800 °C (8 hours)
XRD scan time during holding	20 mins	20 mins
Environment	Wet 4% $\text{H}_2$ 96% $\text{N}_2$ (13.3 cc/min)	Air

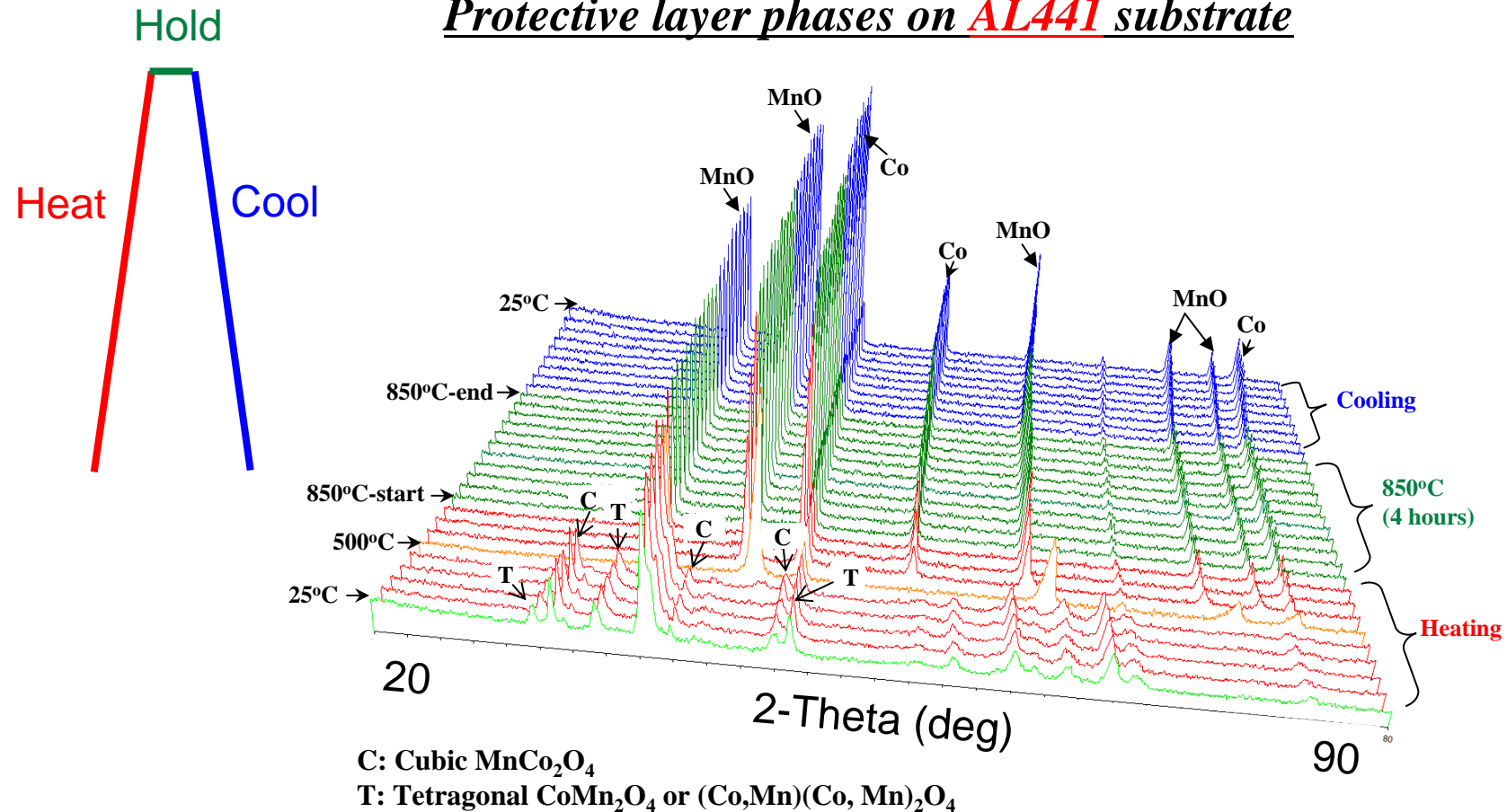
# Results – Phase evolution for reduction cycle



- C + T oxide phases until 400 °C → Transition state 400 – 600 °C → Co + MnO
- Co + MnO are present at the end of the reduction process

# Results – Phase evolution for reduction cycle

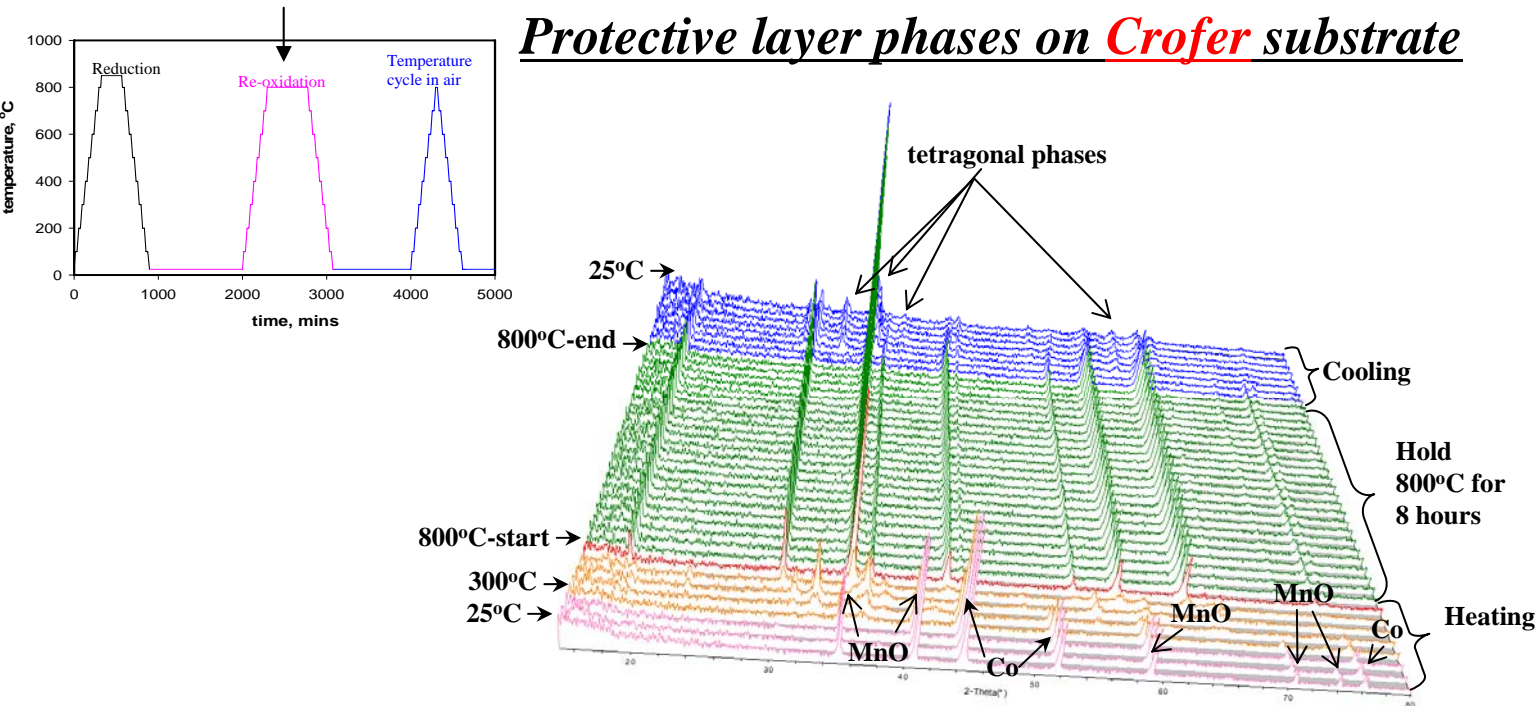
## *Protective layer phases on **AL441** substrate*



- The evolution of the phases in AL441 is the same as the Crofer substrate



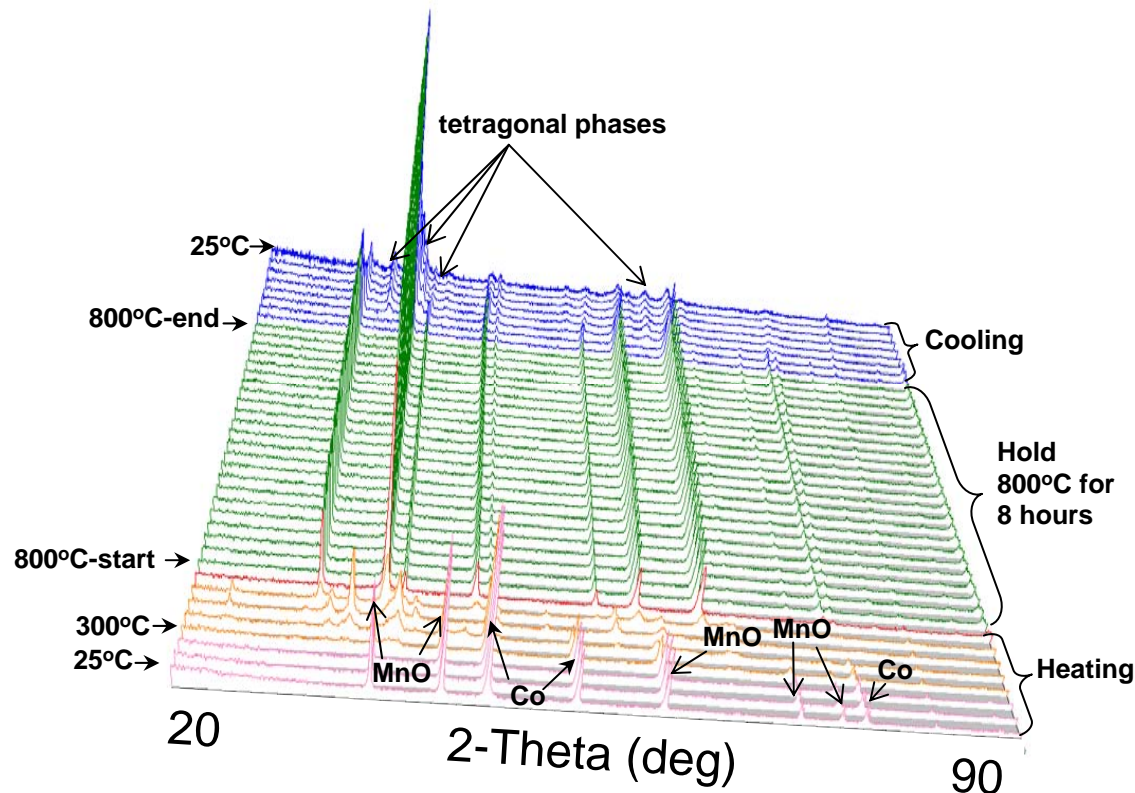
# Results – Phase evolution for re-oxidation cycle



- Co and MnO start oxidizing at 300 °C
- 400 – 500 °C –  $\text{Co} \rightarrow \text{CoO} + \text{Co}_3\text{O}_4$  ;  $\text{MnO (c)} \rightarrow \text{Mn}_2\text{O}_3 \text{ (c)} \rightarrow \text{Mn}_3\text{O}_4 \text{ (t)}$
- 500 °C phases  $\rightarrow$  Tetragonal  $\text{CoMn}_2\text{O}_4$  or  $(\text{Co,Mn})(\text{Co, Mn})_2\text{O}_4$   
+  $\text{Co}_3\text{O}_4 \text{ (c)} + \text{Mn}_2\text{O}_3 \text{ (c)} + \text{Mn}_2\text{O}_4 \text{ (o)}$
- 700 °C and above only cubic  $\text{MnCo}_2\text{O}_4$  is present
- During cooling tetragonal phase appears at 600 °C and cubic and tetragonal spinel phases co-exist below 500 °C

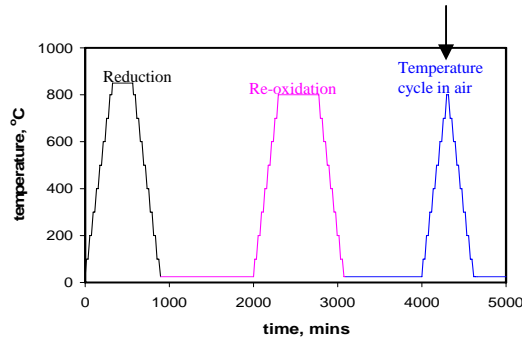
# Results – Phase evolution for re-oxidation cycle

## *Protective layer phases on **AL441** substrate*

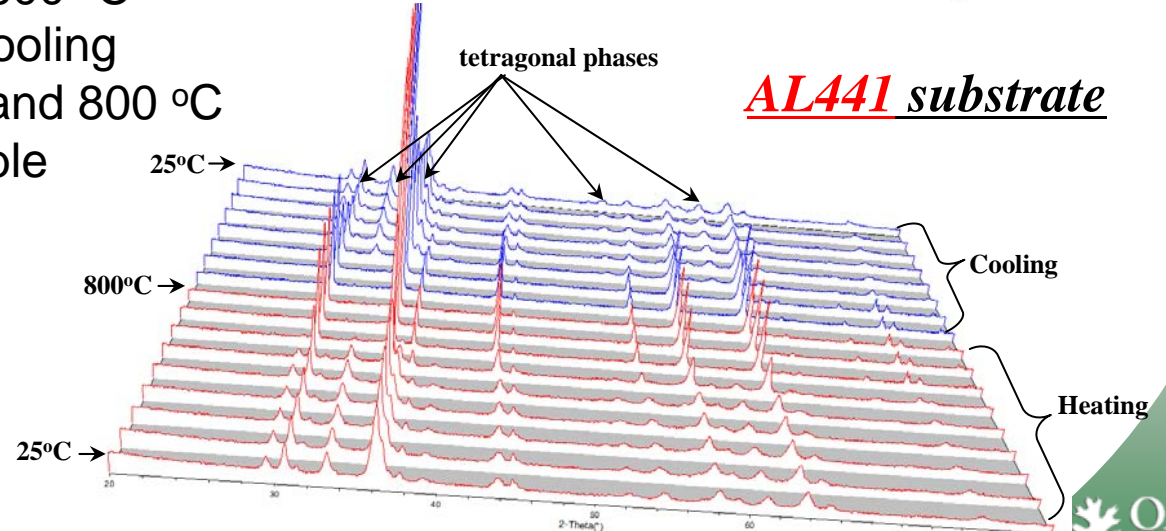
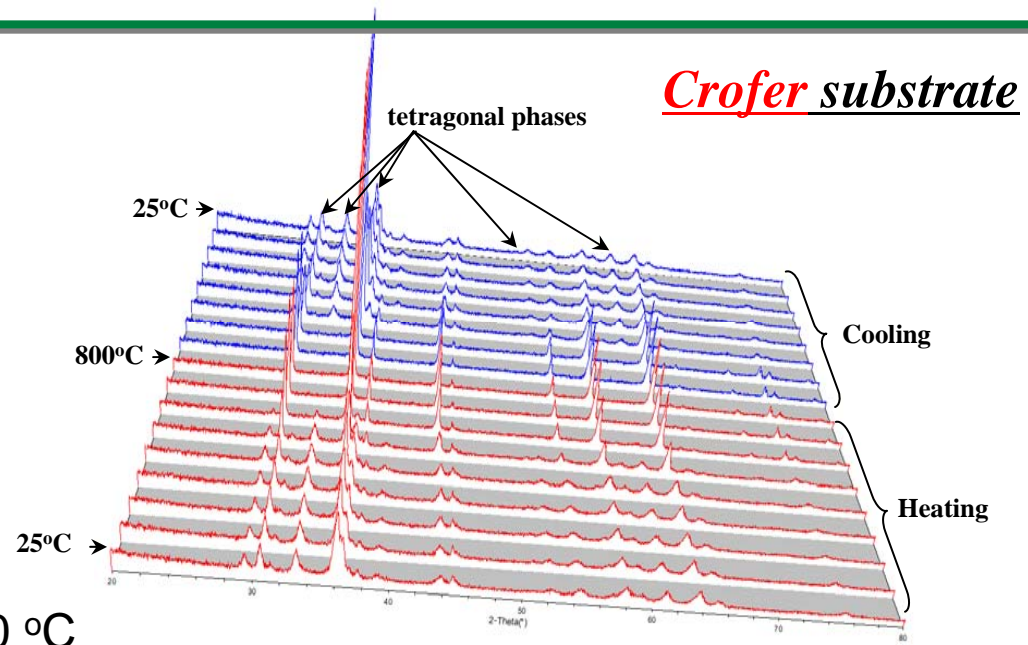


- The evolution of the phases during re-oxidation in AL441 is the same as evolution of the phases on Crofer substrates
- The phase transformations would affect the stress development inside the layers

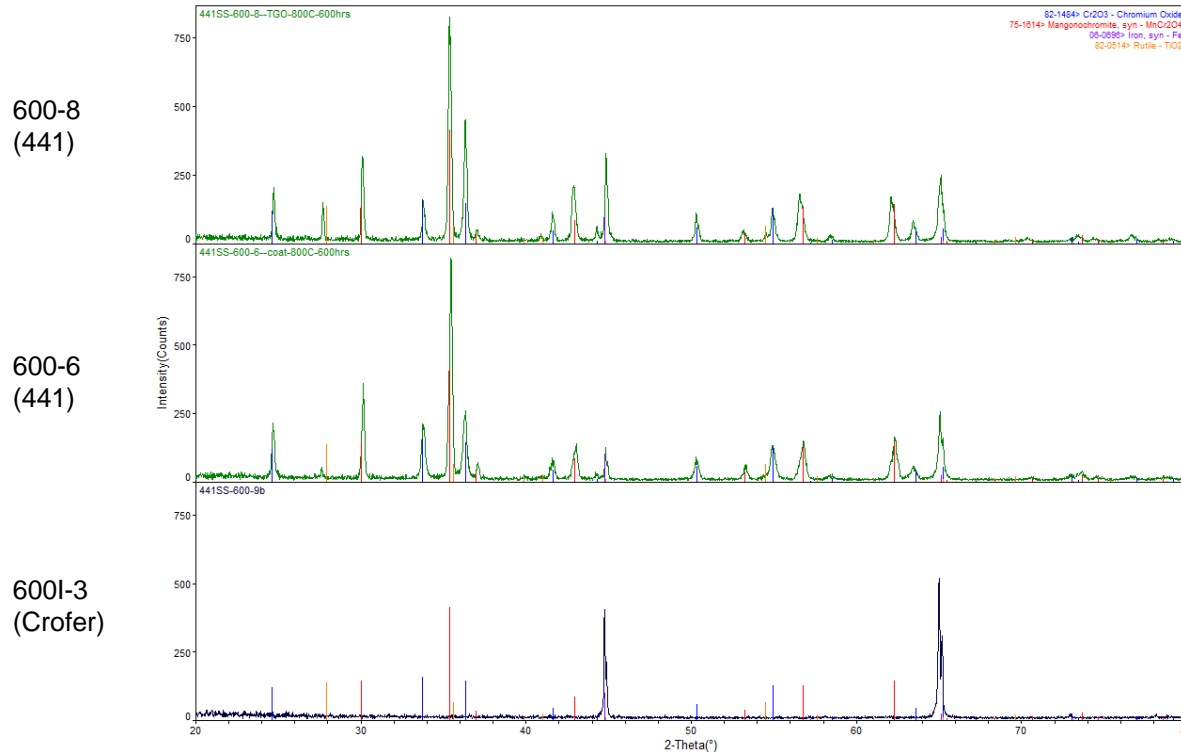
# Results – Phase evolution for Temperature cycle



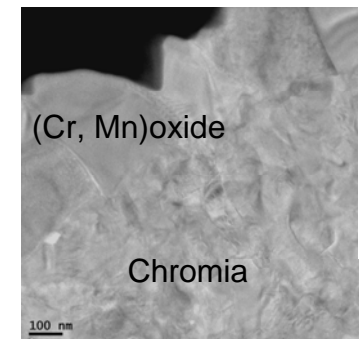
- C + T oxide phases until 600 °C  
- during heating/cooling
- Only cubic phase at 700 and 800 °C
- Transformation is reversible  
for one cycle



# Phases in thermally grown oxide (TGO) layer



Treatment  
800 °C for 600 hours



Phases confirmed by TEM  
analysis (for Crofer)

Sample I.D.	Material	Surface roughness $R_a$ , $\mu\text{m}$	Phases identified through XRD
600-8	441 stainless steel	0.08	$\text{Cr}_2\text{O}_3$ , $\text{MnCr}_2\text{O}_4$ , <b><math>\text{TiO}_2</math></b>
600-6		0.63	
600I-3	Crofer 22 APU	0.1	$\text{Cr}_2\text{O}_3$ , $\text{MnCr}_2\text{O}_4$ ,

- Titanium oxide present on Al441 but not on Crofer

# Summary - Phase evolution for protective layer

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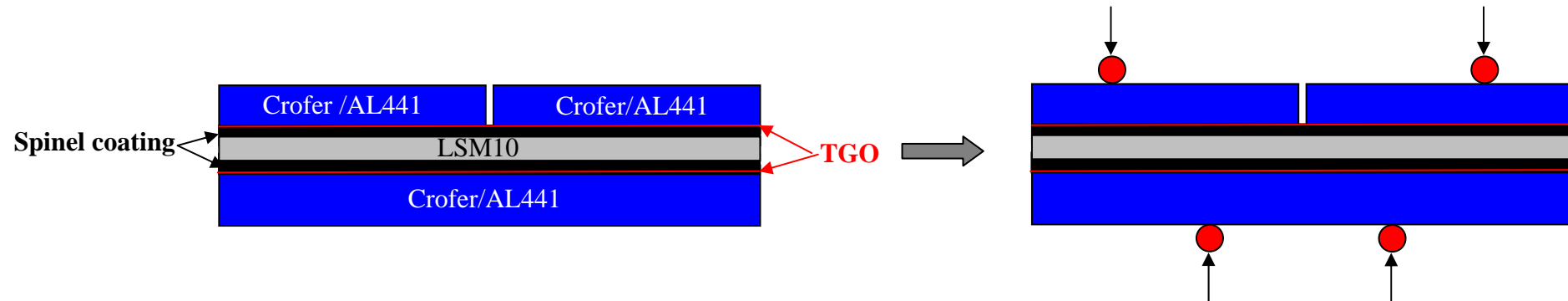
- The phase transformations in the spinel protective layer due to reduction, re-oxidation and temperature cycling were identified.
- Under oxidizing conditions, the cubic spinel  $\text{MnCo}_2\text{O}_4$  is stable at elevated temperatures whereas both cubic and tetragonal phases co-exist at lower temps.
- The phase evolution is important to quantify the residual stresses in the layers.
- Residual stress measurements are in progress at NSLS.

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# Interfacial Characterization



# Sample preparation and testing



- AL441, Crofer22
  - Cut and ground to either 30 or 15 mm in length and 300  $\mu\text{m}$  in thickness with high values of flatness and parallelism
- 15  $\mu\text{m}$  spinel protective layer screen printed
  - Same reduction and re-oxidation procedure as described for phase ID study
- Commercial LSM paste screen printed
  - Sandwich specimen sintered with total LSM layer thickness 60 – 70  $\mu\text{m}$
  - Variables – Sintering conditions (air/cyclic  $\text{pO}_2$ ), temperature, concentration of pore former, thickness of LSM, aging and thermal cycling.

# Calculation of Strain Energy Release Rate

- Four point bending based interfacial fracture energy calculation\*

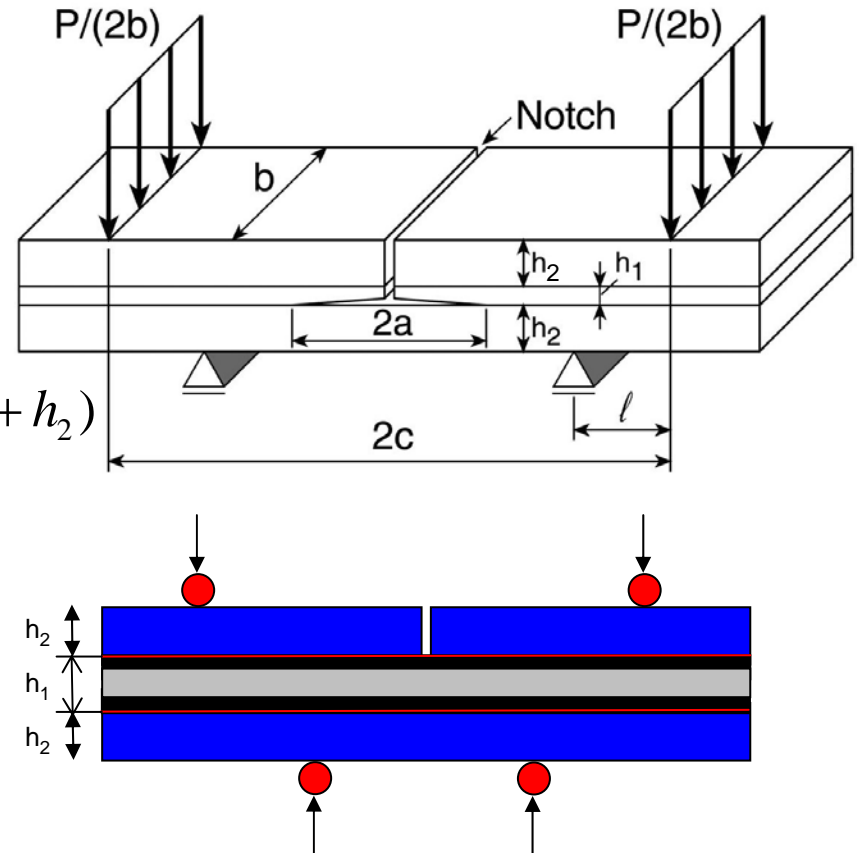
$$G = \frac{(1-\nu^2)M^2}{2E_2} \left( \frac{1}{I_2} - \frac{1}{I_c} \right)$$

$$M = Pl / 2b$$

$$I_c = kh_1^3 / 12 + 2h_2^3 / 3 + h_1h_2(h_1 / 2 + h_2)$$

$$k = \frac{E_1(1-\nu_2^2)}{E_2(1-\nu_1^2)}$$

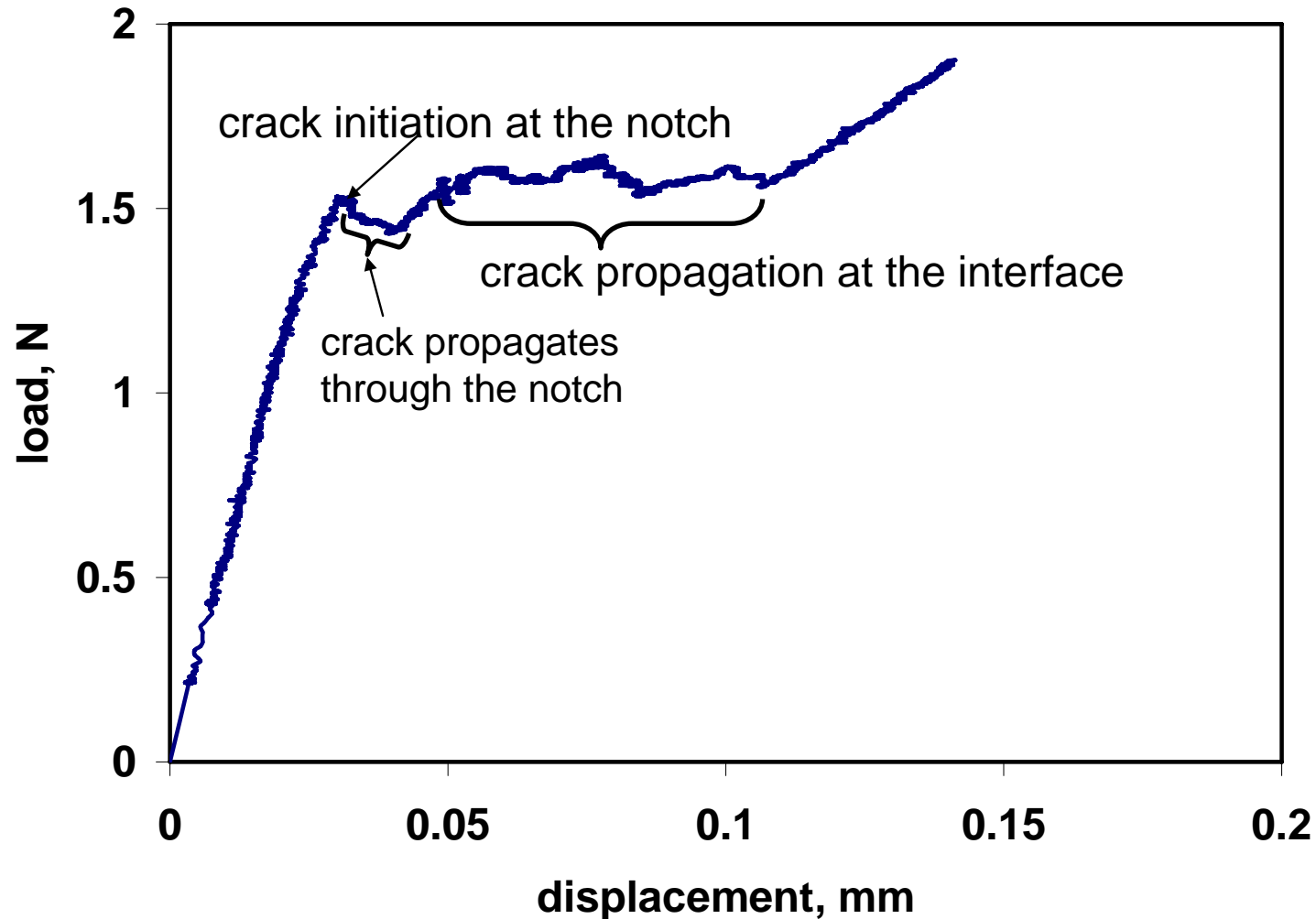
$$I_2 = h_2^3 / 12$$



\* Hofinger *et al.*, International Journal of Fracture **92**: 213-220, 1998.

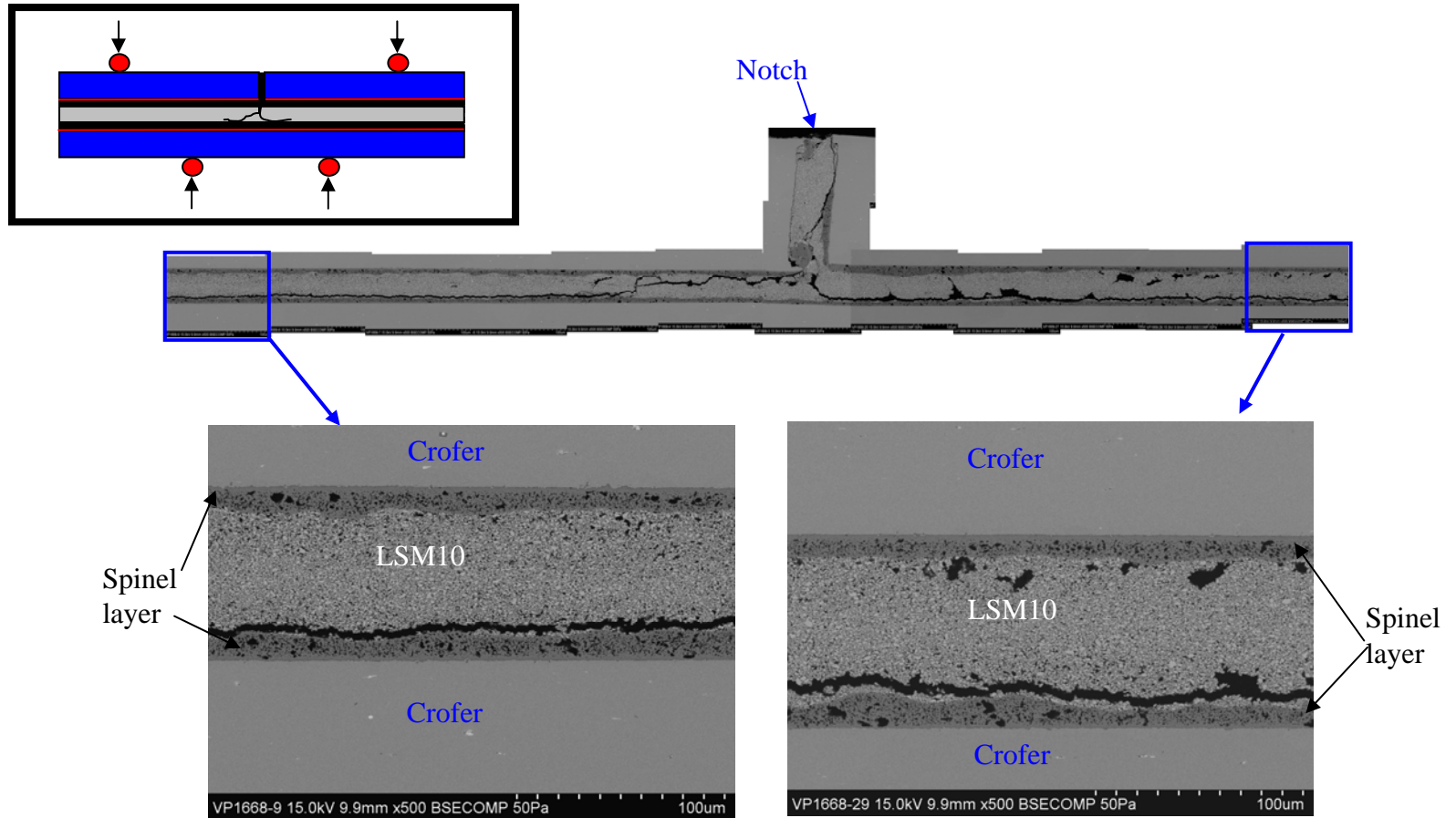


# Example load-displacement behavior



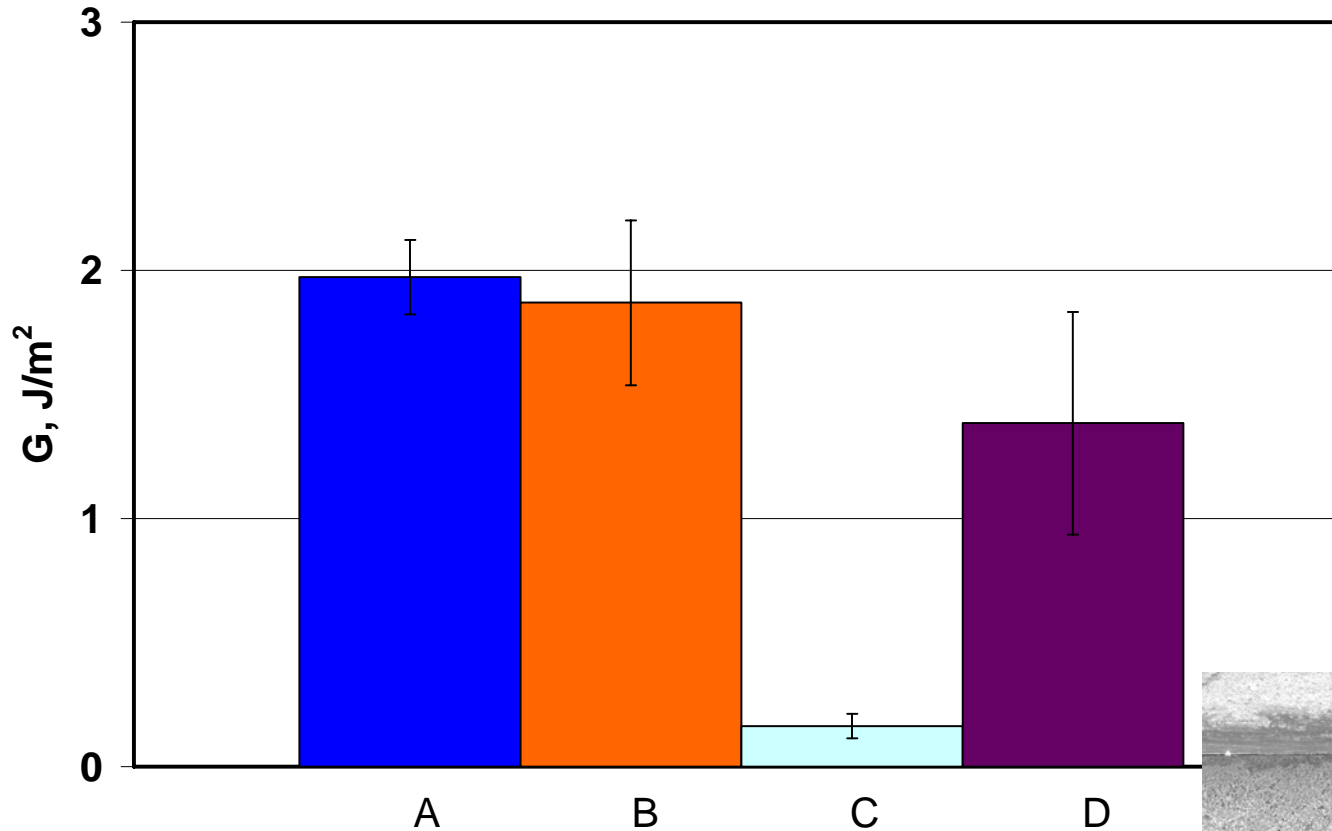
- Steady state load gives a measure of the strain energy release rate of interface

# Crack propagation along interface - SEM



- Crack propagation path is the interface between the LSM10 and spinel protective layer or within the LSM10 layer near the interface
- Mechanical behavior is characterized with test method

# Strain energy release rate variation



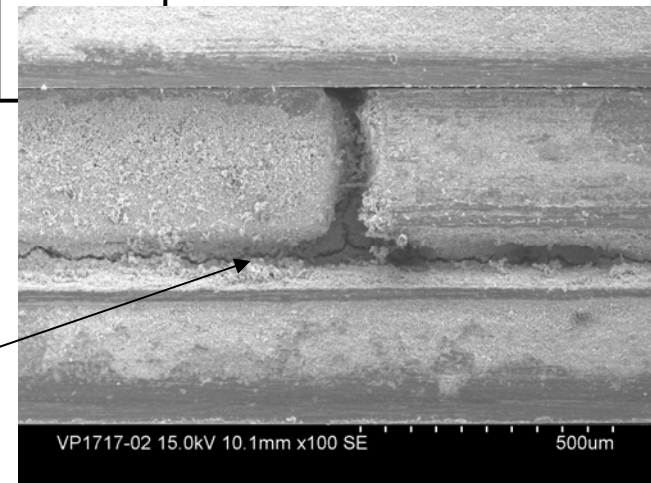
A – 900 °C 4 hours – regular sintering in air (8 tests)

B - 900 °C 4 hours – pO<sub>2</sub> cyclic sintering, 12 cycles (10 tests)

C - 900 °C – 12.5 volume % pore former (2 tests)

D - 1000 °C – 12.5 volume % pore former (4 tests)

Debonding in as prepared specimens for 22.2 % pore former sintered at 900 and 1000 °C



# Summary – Interfacial Toughness

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- A methodology has been established to determine the fracture behavior of metallic interconnects and LSM contact paste interfaces.
- The crack propagation path is identified as the interface between the LSM10 and spinel protective layer or within the LSM10 layer near the interface.
- Preliminary test results show that  $pO_2$  cycling sintering does not influence the interfacial toughness (t-test at the 95% confidence level indicates the difference between the mean values is not significant).

# Summary

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- Phase evolution in the screen printed spinel protective layer and its implications for the mechanical behavior were identified.
- Interfacial toughness testing methodology was developed and implemented.

# Acknowledgments

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